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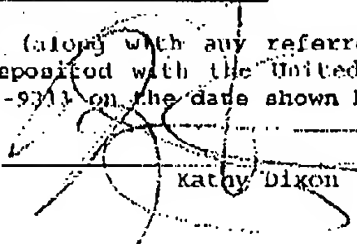
Applicant(s): Chih-Ming Ke	RECEIVED CENTRAL FAX CENTER MAR 11 2004 OFFICIAL
Application No.: 10/047,266 (CONF 4511)	
Filed: 1/14/2002	
Title: Reducing photoresist shrinkage via plasma treatment	
Attorney Docket No.: 67,200-641	Group Art Unit: 1765 Examiner: Kin Chan Chen

Commissioner for Patents
Alexandria, VA 22313-1450

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Date: Mar. 11, 2004


Kathy Dixon

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3/18/04 K-CC

SUPPLEMENTAL AMENDMENT

Dear Sir:

In response to an Advisory Action mailed March 5, 2004, and as a result of a telephone conference with Examiner Chen on March 11, 2004, please enter the following amendments and consider the following remarks.